

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of)
)
 Hiroki et al.)
)
 Serial No.: 09/776,472)
)
 Filed: February 2, 2001)
)
 For: Thin Film Formation Apparatus And)
 Method Of Manufacturing Self-Light-)
 Emitting Device Using Thin Film)
 Formation Apparatus)
)
 Art Unit: 1762)
)
 Confirmation No.: 7144)
)
 Examiner: James Lin)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT (K)

Sir:

Applicants have the following response to the Office Action of December 11, 2006.

Please amend the above-identified application as follows: